



*ITW*

**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q78681

Takayasu YAMAMOTO, et al.

Allowed: January 28, 2005

Appln. No.: 10/721,381

Group Art Unit: 2877

Confirmation No.: 6006

Examiner: Sang H. NGUYEN

Filed: November 26, 2003

For: INSPECTING DEVICE FOR SEMICONDUCTOR WAFER

*please, enter this amendment.*

**AMENDMENT UNDER 37 C.F.R. §1.312**

**MAIL STOP ISSUE FEE**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Pursuant to the provisions of 37 C.F.R. §1.312, please amend the above-identified application as follows on the accompanying pages.

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*Examiner  
SN  
09/15/05*